

Abstract of the Disclosure

A semiconductor wafer ID recognition apparatus includes an image sensing optical section and recognition processing section. The image sensing optical section reads at least one identification information (ID) marked at an arbitrary position on a semiconductor wafer in accordance with a plurality of first read optical conditions registered in advance. The recognition processing section performs recognition processing including calculation of an evaluation score representing a read likelihood ratio for an image output from the image sensing optical section every read optical condition, and adopts a recognition result under a read optical condition exhibiting the highest score as an ID of the semiconductor wafer.